



# 11

**Form PTO-1449** (modified)

List of Patents and Publications

For Applicant's Information

Disclosure Statement

(Use several sheets if necessary)

ATTY. DKT. NO. 5589-04400

APPLICANT: Ashkenaz et al.

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GROUP: 1768 2) - 5

**OTHER ART (Including Author, Title, Date, Pertinent Pages, Etc.)**

	A1	"I300I Guidelines on 300 mm Process Tool Mechanical Interfaces for Wafer Lot Delivery, Buffering, and Loading," (Rev. D, 9/3/96), International 300 mm Initiative, Inc., 6 pgs.
	A2	SEMI E19-0697, "Standard Mechanical Interface (SMIF)," © SEMI 1991, 1997, pp. 1-5.
	A2.1	SEMI E19.1-0697, "Port Standard for Mechanical Interface of Wafer Cassette Transfer, 100 mm (4 inch) Port, © SEMI 1991, 1997, pp. 1-2.
	A3	SEMI E19.5-0996, "Specification for 300 mm Bottom-Opening Standard Mechanical Interface (SMIF)," © SEMI 1978, 1996, pp. 1-4.
	A4	SEMI E21-94, "Cluster Tool Module Interface: Mechanical Interface and Wafer Transport Standard," © SEMI 1991, 1999, pp. 1-7.
	A5	SEMI E21.1-1296, "Cluster Tool Module Interface 300 mm: Mechanical Interface and Wafer Transport Standard," © SEMI 1992, 1996, pp. 1-5.
	A6	SEMI E22-0697, "Cluster Tool Module Interface: Transport Module End Effector Exclusion Volume Standard," © SEMI 1991, 1997, pp. 1-6.
	A7	SEMI E22.1-1296, "Cluster Tool Module Interface 300 mm: Transport Module End Effector Exclusion Volume Standard," © SEMI 1992, 1996, pp. 1-3.
	A8	SEMI E1.9-0699, "Provisional Mechanical Specification for Cassettes used to Transport and Store 300 mm Wafers," © SEMI 1994, 1999, pp. 1-21.
	A9	SEMI E15-0698, "Specification for Tool Load Port," © SEMI 1990, 1998, pp. 1-8.
9/11 OK'd 5-2	A10	SEMI E15.1-0200A, "Provisional Specification for 300 mm Tool Load Port," © SEMI 1996, 2000, pp. 1-11.
	A11	SEMI E15.1-0600, "Specification for 300 mm Tool Load Port," © SEMI 1996, 2000, pp. 1-11.
	A12	SEMI E47-0301, "Specification for 150 mm/200 mm Pod Handles, © SEMI 1995, 2001, pp. 1-4.
	A13	SEMI E47.1-0301, "Provisional Mechanical Specification for Boxes and Pods used to Transport and Store 300 mm Wafers," © SEMI 1997, 2001, pp. 1-21.
	A14	SEMI E57-0600, "Mechanical Specification for Kinematic Couplings used to Align and Support 300 mm Wafer Carriers," © SEMI 1996, 2000, pp. 1-7.
	A15	SEMI E62-0701, "Provisional Specification for 300 mm Front-Opening Interface Mechanical Standard (FIMS)," © SEMI 1997, 2001, pp. 1-9.
	A16	SEMI E63-0600A, "Mechanical Specification for 300 mm Box Opener/Loader to Tool Standard (Bolts-M) Interface," © SEMI 1997, 2000, pp. 1-7.
	A17	SEMI E64-0600, "Specification for 300 mm Cart to SEMI E15.1 Docking Interface Port," © SEMI 1997, 2000, pp. 1-5.

EXAMINER:

*Garland*

DATE CONSIDERED:

9/22/04

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